

Agilent Ref: 10021235-1  
United States Application Serial No. 10/670,551

**AMENDMENTS TO THE CLAIMS**

Please enter the following amendments.

1. (Currently Amended) A structure for the construction of one of a microscale and nanoscale device, comprising  
a rigid frame supporting a diaphragm comprising a first material, the diaphragm having an opening therethrough,  
a region of a second material disposed in the opening and supported by the diaphragm,  
wherein the diaphragm is in tension ~~first material and the second material are different.~~
2. (Original) A structure as recited in claim 1, wherein the diaphragm comprises a layer of a silicon nitride.
3. (Original) A structure as recited in claim 1, wherein the second material comprises one of polyimides, photoresists, Parylene®, organic molecules, inorganic molecules, metal, and insulators.
4. (Original) A structure as recited in claim 1, wherein the second material comprises polyimide.
5. (Original) A structure as recited in claim 1, wherein the nanoscale device is nanopore.
6. (Previously Presented) A structure as recited in claim 2, wherein the silicon nitride layer is from 100 nm to 300 nm in thickness.
7. (Previously Presented) A structure as recited in claim 2, wherein the silicon nitride layer is about 200 nm thick.

DO NOT ENTER  
-NOT 8/1/05